

CMOS PIXELS SENSORS ACTIVITIES AT IRFU

FCC-Saclay meeting

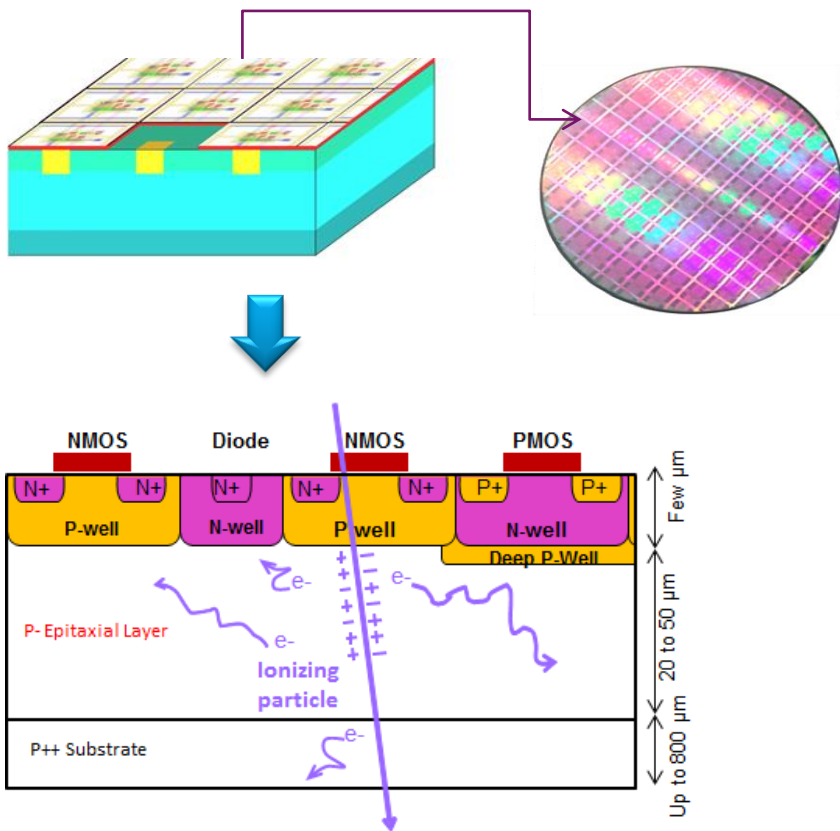
F. Orsini

26th November 2015

MAPS = Monolithic Active Pixels Sensor

Solid detector in Silicon

Sensible volume (detection part) + signal processing circuit share same substrate, using standard CMOS electronic components = 'CMOS Monolithic'

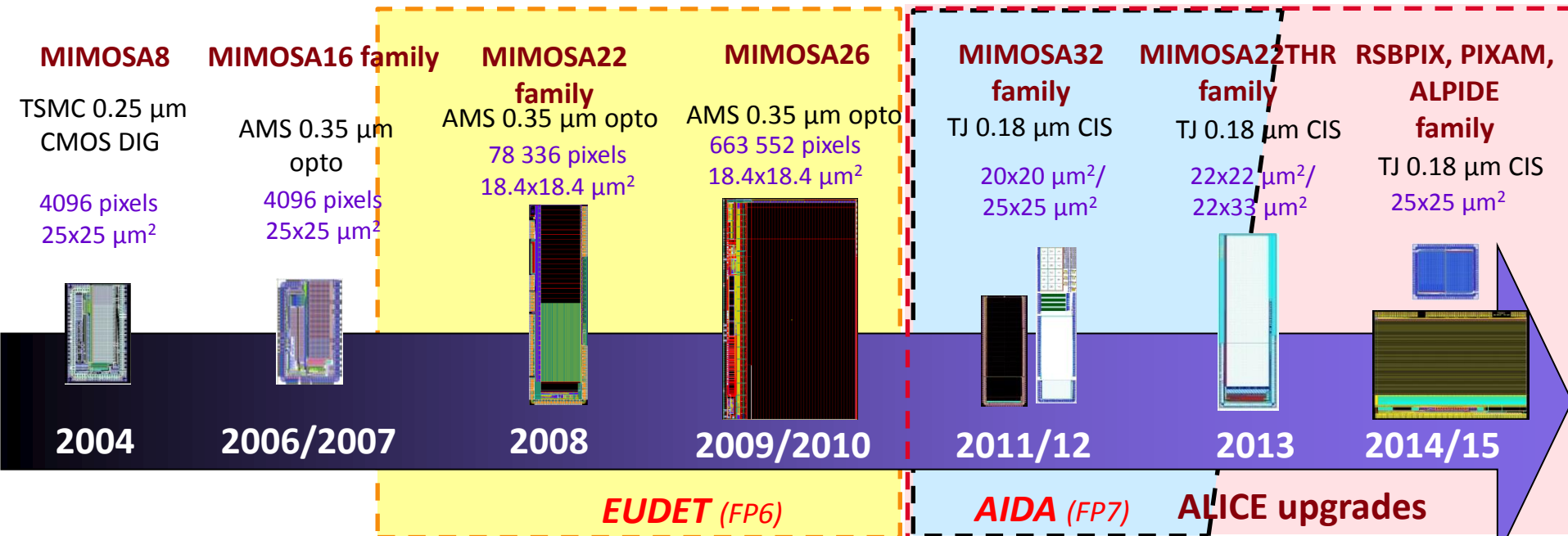


Main advantages

- High Granularity
- Monolithic and ultra-thin
- Low noise, low power
- Work at ambient temperature
- Low cost (CMOS process)

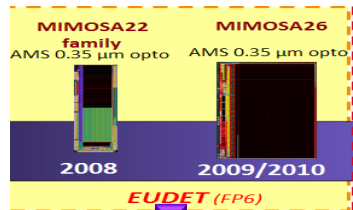
HISTORIC – CMOS MONOLITHIC PIXELS SENSORS DEVELOPMENT AT IRFU

- Since ~2002 IRFU has launched a R&D program on CMOS MAPS technology starting in the framework of the ILC project (vertex detector)
- Y. Degerli (SEDI) has designed the first digital MAPS (MIMOSA 8) jointly with IPHC
- ~20 MAPS **with digital outputs** have been designed, realized and tested in the past 10 years (from small prototypes to large sensors) in collaboration with IPHC for **ILC VX, EUDET (FP6), AIDA (FP7)** and recently for **ALICE-upgrade projects** (MAPS design effort driven by CERN consortium)
- It has demonstrated the validity, maturity and the excellent performances of this detection technology for charged particles tracking





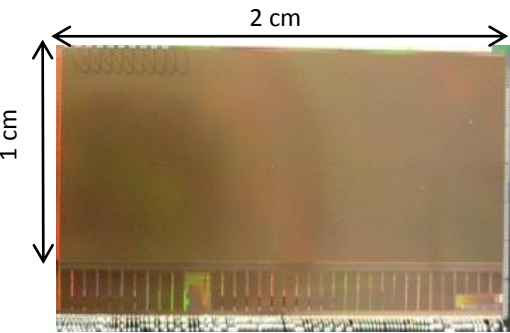
FP6



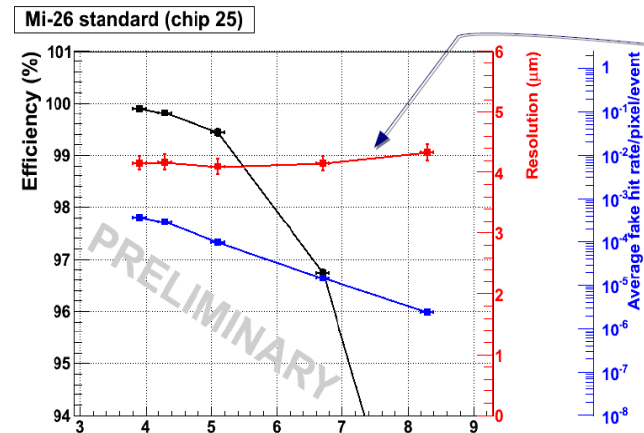
EUDET (JRA1) Beam Telescope

6 planes composed of MIMOSA26 sensors

Technology: AMS 350 nm (opto)
Designed by IPHC-IRFU (Y. Degerli for IRFU)



MIMOSA 26
663 552 pixels – pitch = 18.4 μm



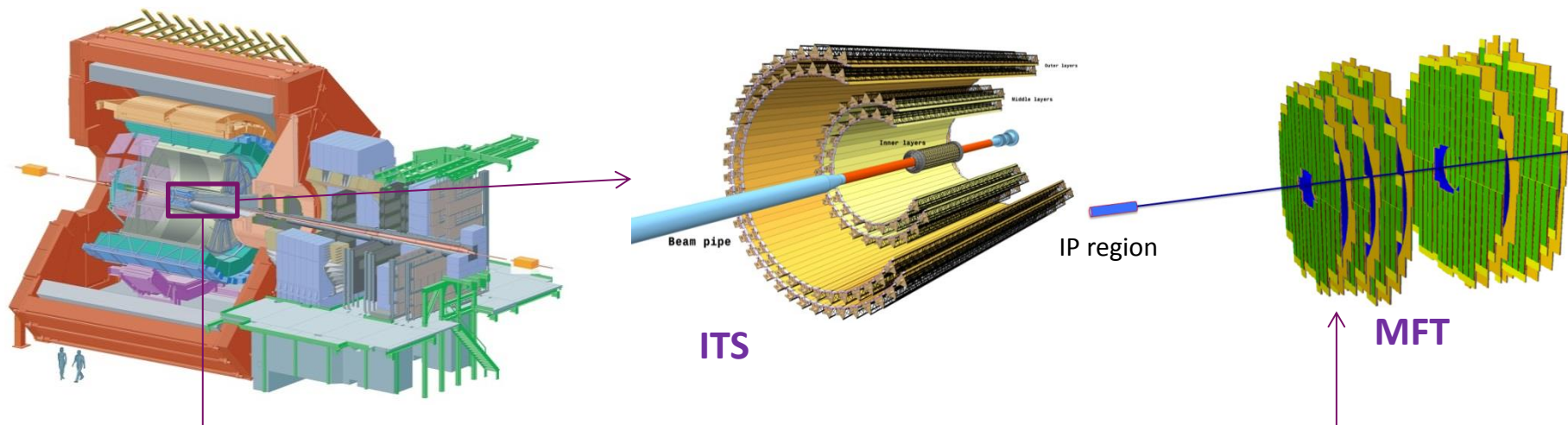
- ❑ Large size Digital MAPS integrated for the first time in a physics experiment (MIP tracking)
 - work with success → few copies of the telescope around the world (DESY, CERN, US)

❑ Performances achieved:

- ❑ Integration/readout time: 115 μs (per frame)
- ❑ Detection efficiency > 99.5%
- ❑ Spatial resolution (digital output): 4 μm
- ❑ Rad tolerance: Dose of 500 kRad and neutron fluence of $\sim 1.10^{13} n_{eq}/cm^2$

AIDA, ALICE upgrades

CMOS MONOLITHIC PIXELS SENSOR FOR ALICE UPGRADE: ITS & MUON FORWARD TRACKER



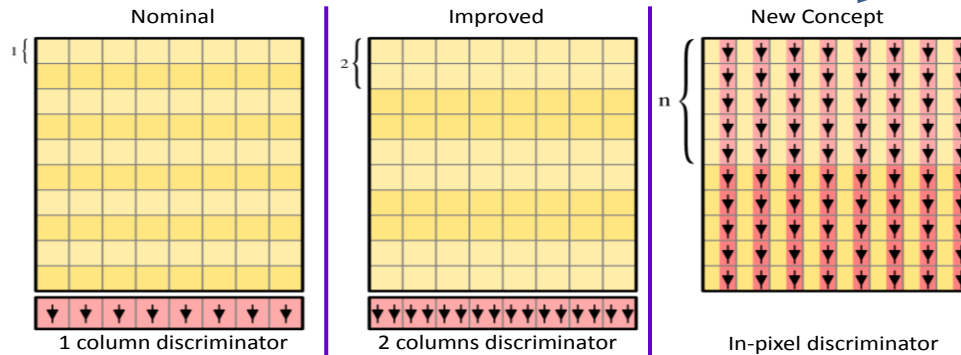
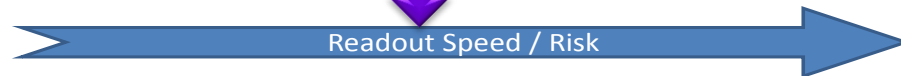
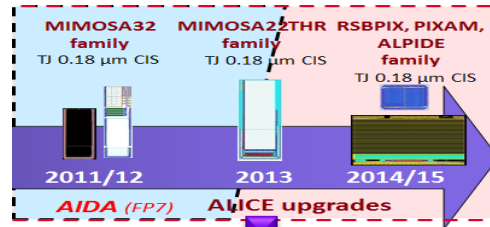
ITS upgrade:

- 7-layers barrel geometry based on MAPS
($\sim 25\,000$ sensors $\sim 10\text{ m}^2$)
- η coverage: $|\eta| \leq 1.22$

Muon Forward Tracker: vertexing for the ALICE Muon Spectrometer at forward rapidity

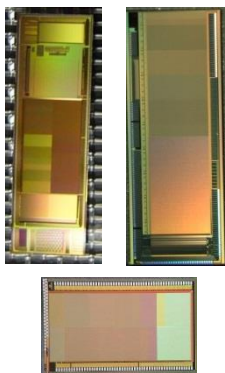
- 5-planes geometry based on MAPS (~ 900 sensors, $\sim 0.5\text{ m}^2$)
- η coverage: $-3.6 < \eta < -2.45$

| Parameter | Value |
|---|--|
| Spatial Resolution | $\sim 5\ \mu\text{m}$ |
| Detection Efficiency | $> 99.5\%$ |
| Integration Time | $< 20\ \mu\text{s}$ |
| Sensor Thickness | $50\ \mu\text{m}$ |
| Power dissipation | $< 150\ \text{mW}/\text{cm}^2$ |
| Radiation Tolerance (10-years operation) | $\sim O(10^{13})\ n_{\text{eq}}/\text{cm}^2$ $\sim O(800)\ \text{kRad}$ |



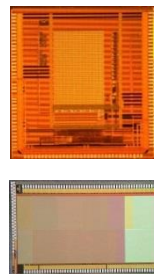
Techno choice
 Tower Jazz 180 nm
 High Resistivity epi-layer (> 1 kΩ.cm)

M32, M32Ter, M32v4
 M22THRA2



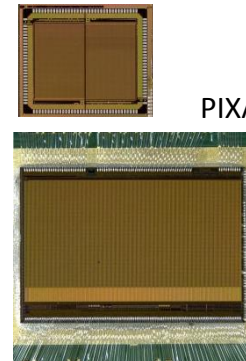
- Digital outputs
- Medium size proto.
- 1 discri. / column
- RO speed X1

M32v4 (analog part)
 M22THRB2



- Digital outputs
- Small size proto.
- 2 discri. / column
- RO speed X2

M32v4 (analog part)
 RSBPIX1, RSBPIX2



PIXAM

- Digital outputs
- Small and large size proto.
- 1 discri. / pixel
- RO speed X2

PIXAM (FSBB prototype) for the ALICE - Muon Forward Tracker

Tower Jazz 0.18 μm CIS technology

Submitted in May 2014

1/3 of final matrix (10 mm \times 7 mm)

2 lines readout simultaneously

- Readout time nominal : 15.36 μs
- Evaluation for readout : 10 μs

Rolling Shutter Binary Pixel architecture

- 25 μm pitch
- In each pixel: amplification, CDS, discriminator with continuous offset compensation

Zero suppression logic

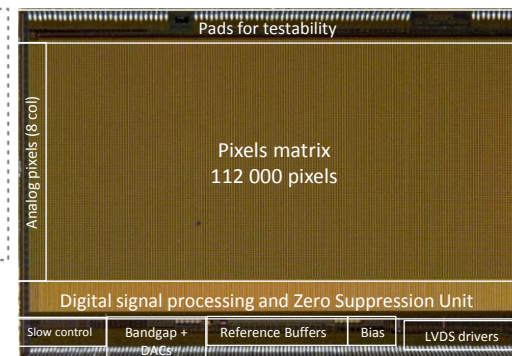
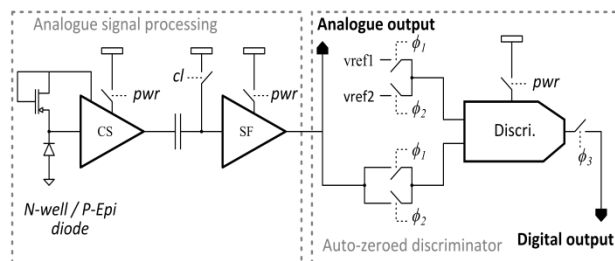
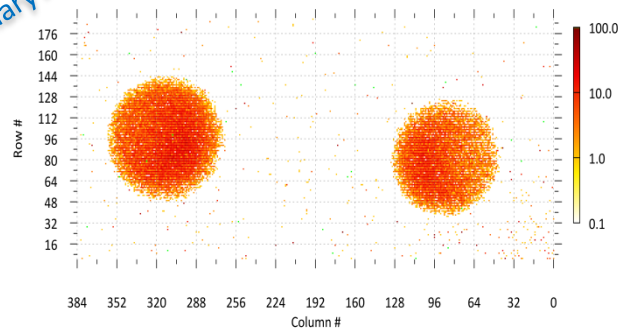
- Cluster 3x3 pixels
- 7 clusters / row/ FSBB

Digital Outputs

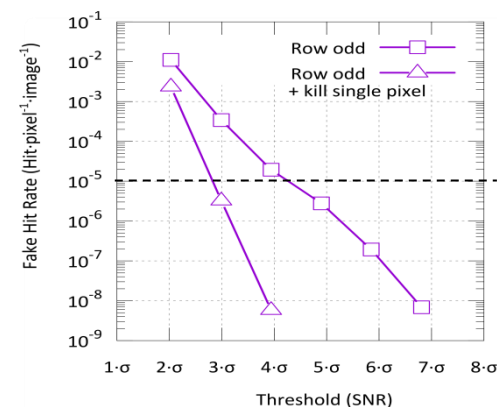
- Compatible with Pxi DAQ

Power Dissipation (estimation)

- Analog: 105 mW/cm² (not optimized)
- Digital: 45 mW/cm²

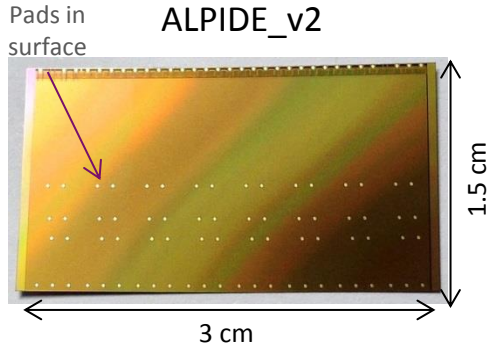
Tests in-lab
Preliminary resultsWith Fe⁵⁵ source

Fake Hit Rate



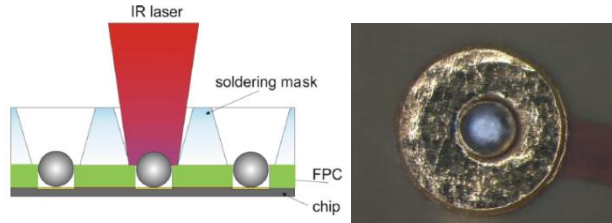
➔ Y. Degerli, C. Flouzat, F. Guilloux

L. Musa (ITS-CERN) – June 2015



Readout time = 4 μ s

Interconnection of CMOS sensor to Flex PCB by laser soldering technique

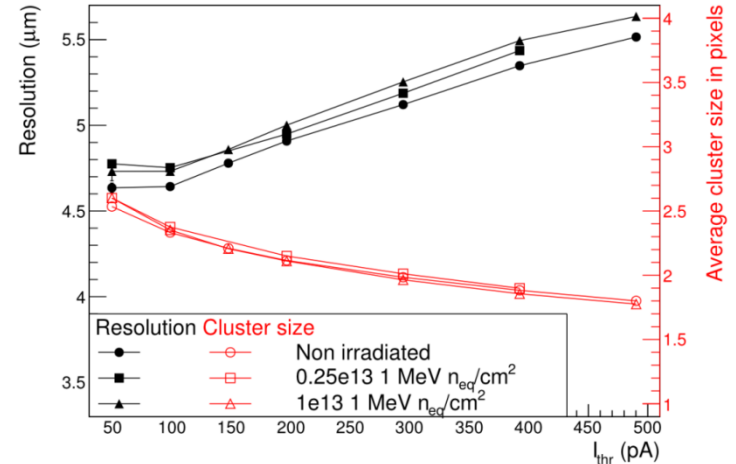
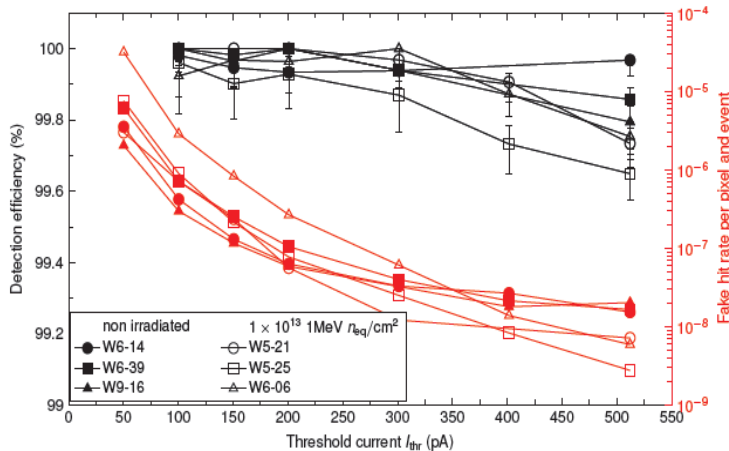


MFT Ladder prototype with fake sensors

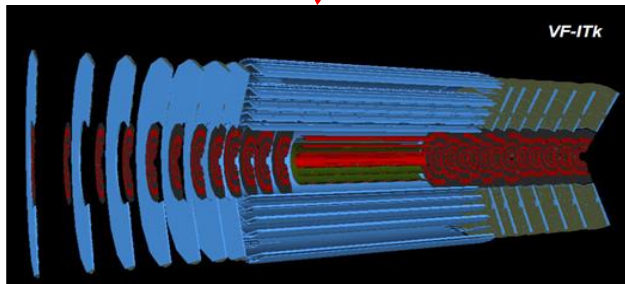
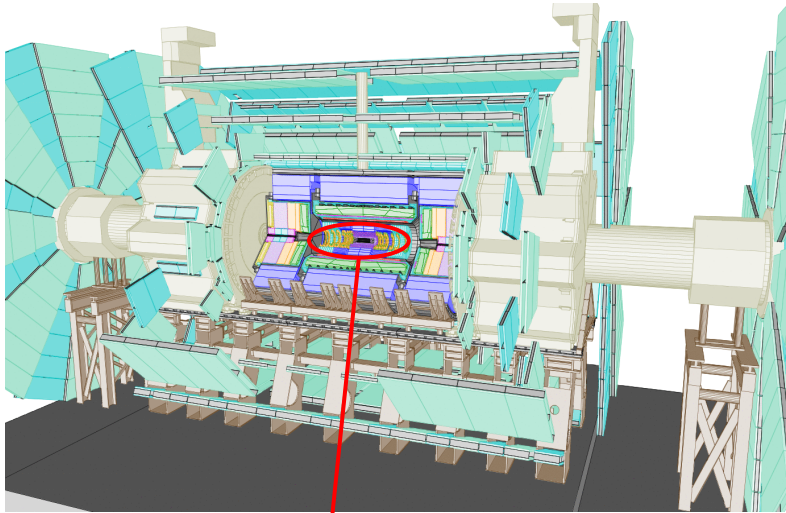


⇒ High resistivity ($> 1\text{k}\Omega\text{ cm}$), p-type epitaxial layer (20 μm – 40 μm thick) on p-type substrate

Example of measurement at PS (5 – 7 GeV π^-) test beam with pALPIDEs_v1 (Dec 2014/March 2015)



with 50 μm thick chips: non irradiated and irradiated with neutrons (0.25×10^{13} and 1×10^{13} 1MeV n_{eq}/cm^2)



Challenges for phase II

- Radiation hardness
- Readout time (high rates)

| | ATLAS-LHC | ATLAS-HL-LHC |
|---|--------------------|--------------------|
| Bunch crossing [ns] | 25 | 25 |
| Particles rate [kHz/mm ²] | 1000 | 10000 |
| Neutrons flux [n _{eq} /cm ²] | 2x10 ¹⁵ | 2x10 ¹⁶ |
| Dose (ionizing part) [MRad] | 80 | >500 |

Inner barrel

- High resistivity wafer
 - Application of high voltage → complete depletion of bulk possible
- +
- Material budget improvement
 - Thinner granularity
 - Cost improvement
- =

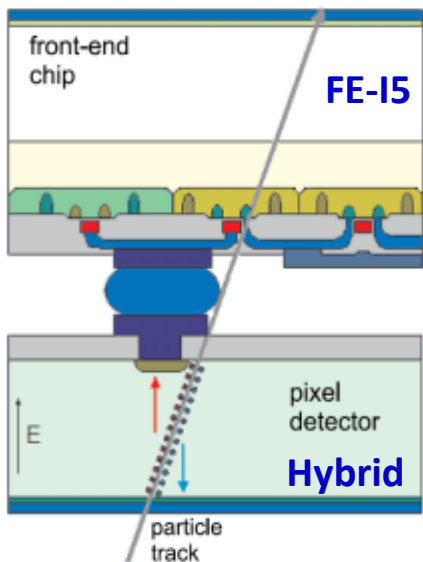
➔ HV/HR CMOS Pixels

ATLAS PHASE II INNER TRACKER: CANDIDATES

Present = hybrid pixels for inner layers and strips for outer layers → to be replaced

BASELINE

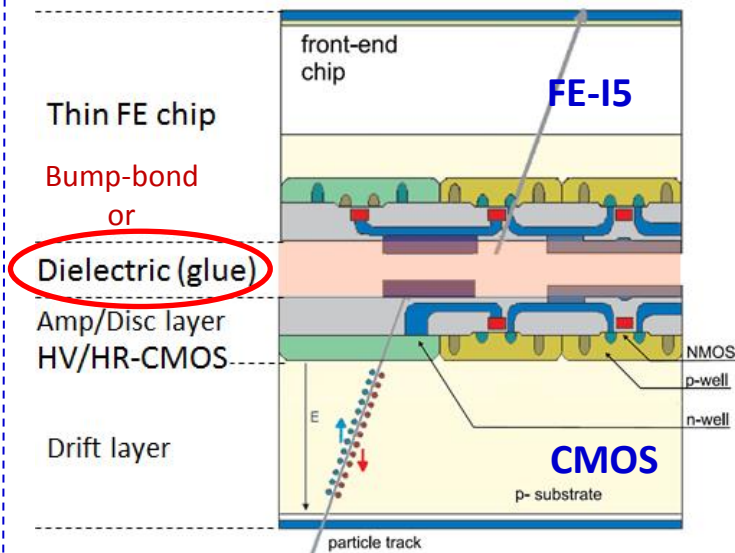
'Standard' Hybrid
Pixels + FE-15



- Rad hardness
- Fast readout
- Thick, Low granularity
- High Cost
- QA pb for large prod

CONCURRENCE

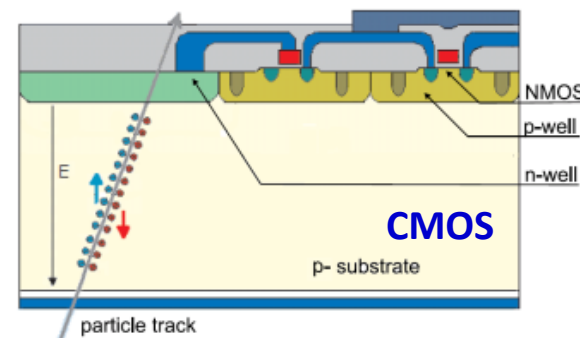
[Middle-Outer layers]
HV-(HR)CMOS + FE-15



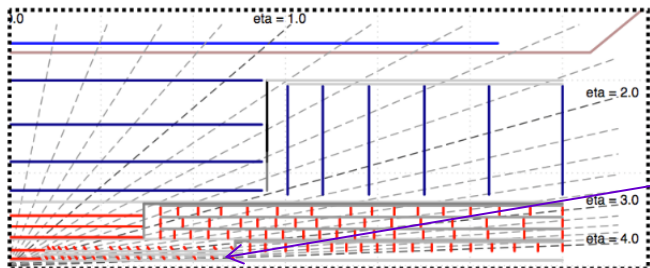
- More granular
- Less expensive (cheaper bonding process)
- Thinner
- Low power, low noise
- Rad hardness

OUTSIDER

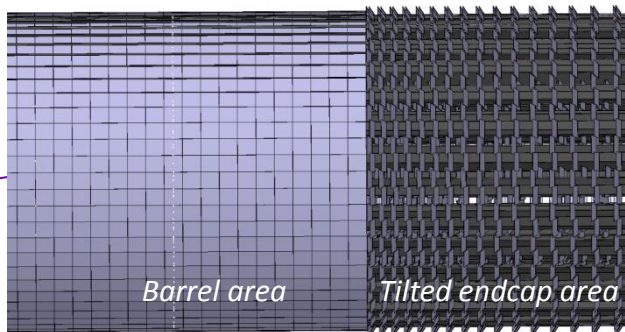
[Middle-Outer layers]
HV-(HR)MAPS
(full monolithic)



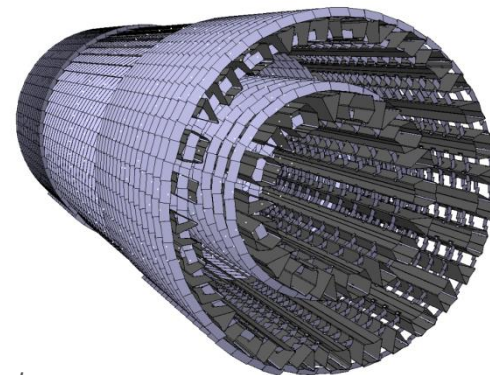
- Highest granularity
- Thinnest (material budget \searrow)
- Lower cost (intelligent detector)
- Low power, low noise
- Rad hardness, fast readout



ITK possible layout: Inclined@4.0

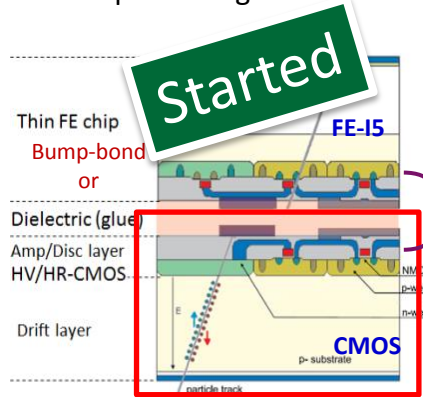


SLIM concept



1 HVCMOS pixels sensor design

Design and validation of HVCMOS pixels sensors concept (incl. 1st amplifier stage + add circuits)

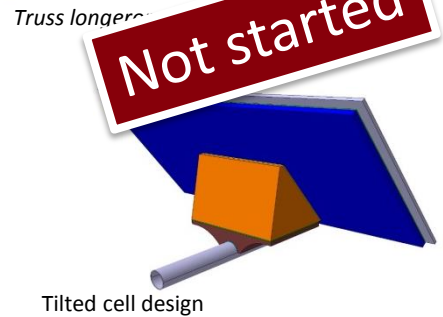


2 Interconnection studies

Readout via ATLAS pixel chip FE-I4 capacitively coupled



3 Thermomechanical studies



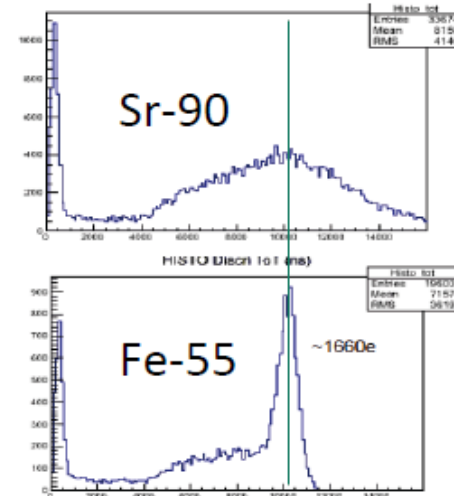
S. Rozanov – CPPM

| | A | B | C | D | E | F | G | H | I |
|----------------------|---|---|---------------|---------------------|-------------------|----------------|---|------------------|---------------|
| Node | 180nm | 350nm | 150 nm | 180nm SOI | 180nm | 130nm | 150nm | 130nm | 160nm |
| Wafer Resistivity | 10 ohm | 10 ohm 1 kohm availab | 2 kohm | 100 ohm 2k poss. | 1-3 k Epi/bulk | 3k | 2k | 10 ohm 3k ??? | Select epi |
| Full CMOS | No | No | Yes | yes | Yes | No | Yes | Yes | Yes |
| Backside implant | No | No | Yes | No | No | No | Yes | No | No |
| HEP experience | 4 subm Lab Test beam | 2 subm Labor Also strips Demo 11/2015 | 2 subm Lab | Subm Lab | Subm Lab | Subm 6/2014 | Receiv 2/2015 Demo 12/2015 | Receiv Lab | tbd |
| Groups | Heidelb Geneva CPPM Bonn CERN | Karlsruh. Geneva | Bonn Prag. | Bonn CERN | Bonn (Strasb) | Bonn | Bonn, Heidel. CPPM, IRFU CERN, SLAC | CPPM Heidel. | INFN |

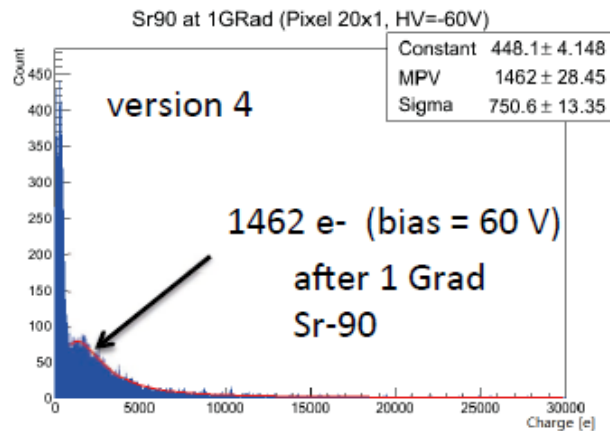
AMS 180 nm (bonded to FE-I4)

some encouraging results

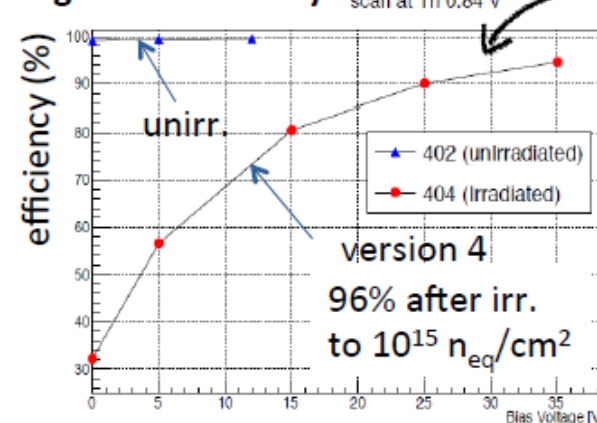
- capacitive coupling seems to work in principle, whether it is competitive in terms of reliability and price is unclear
- **chips stand TIDs up to 1 Grad**
- proton irradiation $10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$ performed
- **efficiency (time integrated): 99% -> 96%**
- in-time efficiency not yet met ($\tau_{\text{rise}} \sim 100 \text{ ns}$)
- signal $\sim 1500 \text{ e}$; SNR ~ 25
- characterizations w/o FE-I4 ongoing



version 2
before
irradiation



time integrated efficiency



Need to reach the plateau

HVCMOS SENSORS DESIGN & PERFORMANCES CHARACTERIZATION ACTIVITIES

□ Current Team (2015)

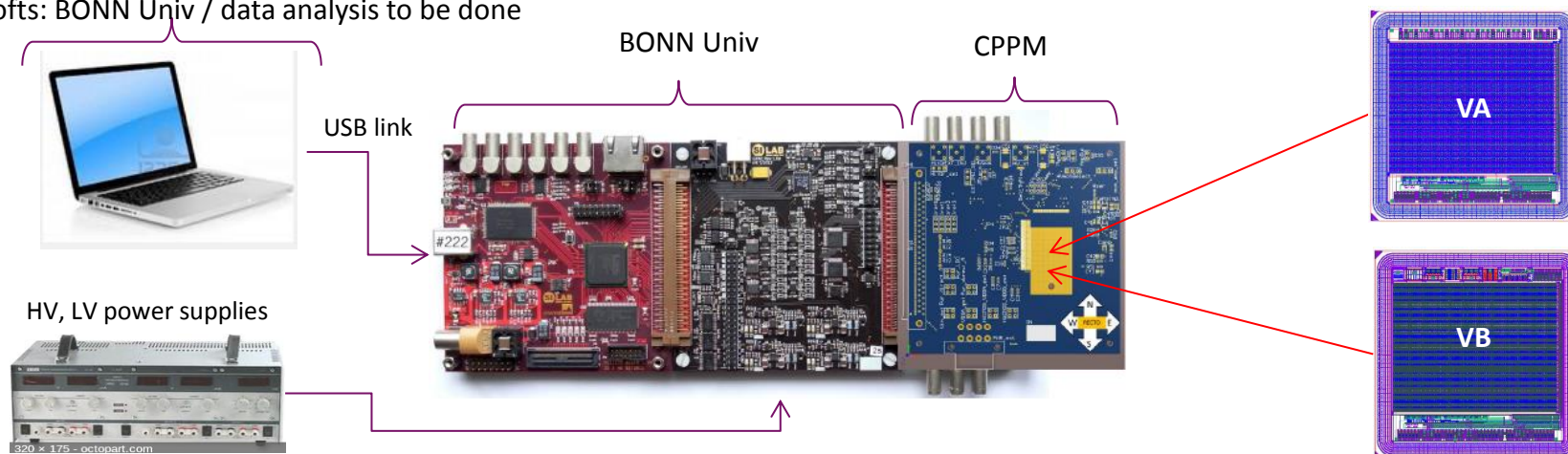
- Microelectronic Design, techno process:
Yavuz Degerli (+ punctual help from F. Guilloux and F. Bouyjou)
- Project coordination, techno process, protos performance tests:
Fabienne Orsini
- ATLAS physicists:
Claude Guyot, Philippe Schwemling
- PhD student:
Mohamed Lachkar (since October 2015; design, tests and TCAD simulations)

□ HVCMOS Activities

- Started with the GF 130 nm process in collaboration with CPPM, and then switched to the LF 150 nm process with CPPM and Bonn
- Participation to the tests of CCPD_LF prototypes (*just started...*)
- Currently, active participation to the design of a demonstrator in LF 150nm HV techno process
- Participation to H2020 project (start in June 2015):
AIDA2020 WP6 "Novel high voltage and resistive CMOS sensors"

CCPD_LF PROTOTYPES PERFORMANCES CHARACTERIZATION TESTS

Acq softs: BONN Univ / data analysis to be done



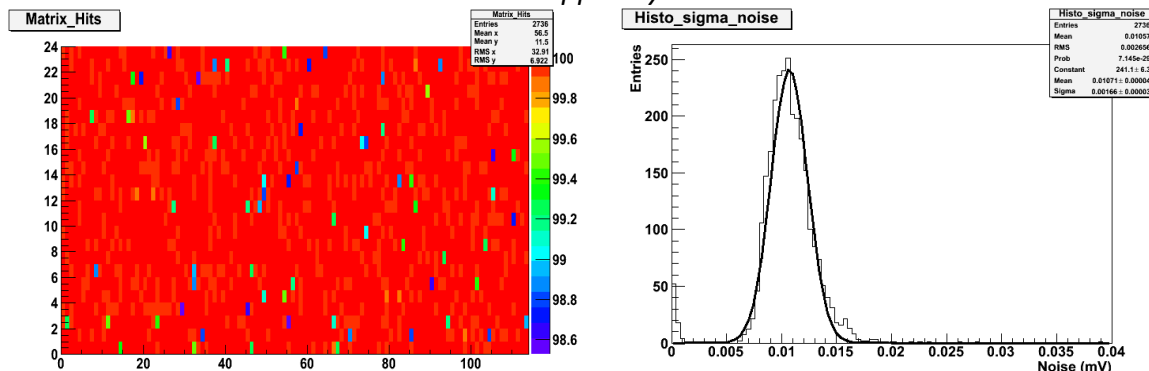
*Very first scan tests to check testbench assembly and softs functioning at IRFU
No HV applied yet*

LF 150 nm HV technology

- Chip size: 5 mm × 5 mm
- Matrix: 24 × 114 pixels
- Pixel size: 33 μm × 125 μm
- VA: negative HV applied on P-substrate
- VB: positive HV applied to DNWell

Objectives:

- Participate and provide to the collaboration tests results of the different CCPD_LF prototypes config.
- Better understanding of the chip architecture (strengths, weaknesses)



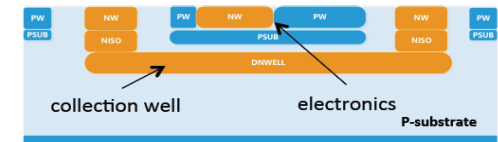
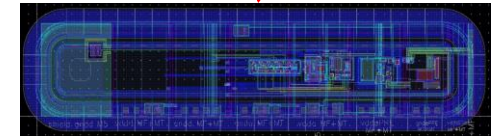
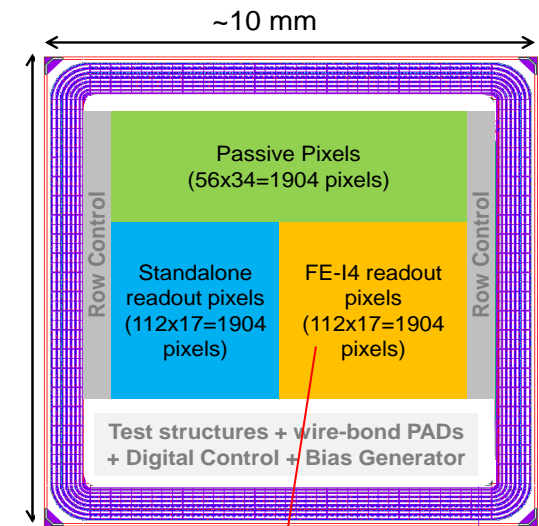
Demonstrator Process: LFoundry 150nm HVCMOS

Bonn, CPPM, IRFU collaboration

- ❑ Based on experience with 2 previous CCPD_LF prototypes designed by Bonn&CPPM in 2014
- ❑ Passive, Standalone digital and analog/digital output pixels (FE-I4 readable)
- ❑ A more performant pre-amplifier is proposed by IRFU
- ❑ Pixel properties:
 - Pitch: **250 μ m x 50 μ m**
 - Peaking time: **~20 ns**
 - Power dissipation: **~20 μ W** (analog)
- ❑ Re-use of already validated peripheral circuits
- ❑ Close to being completed, submission planned in Dec. 2015

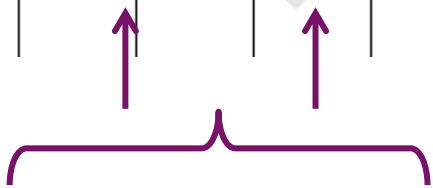
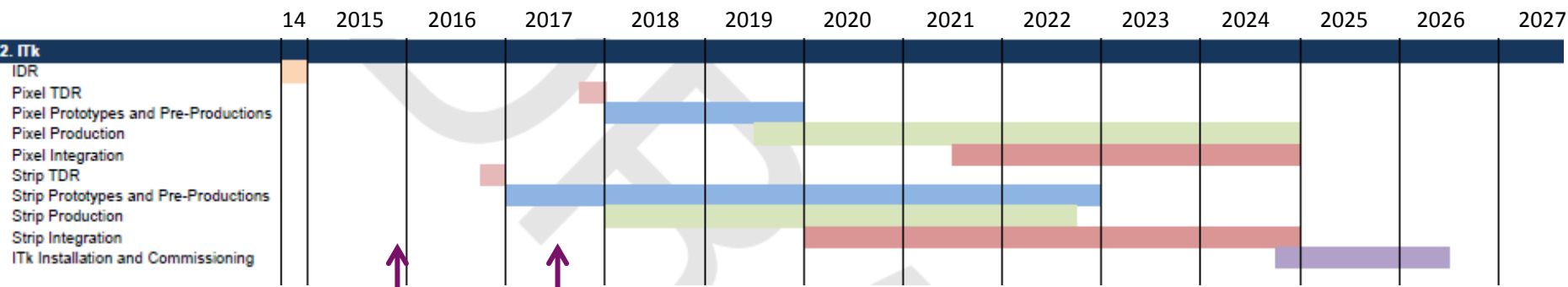
Objectives:

- Demonstrate the performances of HVCMOS chips to expected ITK irradiations level
- Be ready for pixels techno choice in 2017 and for Pixels-TDR in Q4 2017



Digital pixel layout

Time-line of ITK upgrade project



HVCMOS main tasks

- Demonstrator back from foundry (5 m) May 2016
- Post processing of circuits (1 m) June 2016
- Demonstrator performances validation (4 m) Oct 2016
- 2nd demonstrator submission Dec 2016
-
- Preparation of pixels TDR June 2017
- Pixels TDR submission Q4 2017

Choice for techno →

OTHER POSSIBLE PARTICIPATION IN MICRO-ELECT ACTIVITIES FOR ATLAS ITK (PROPOSAL)

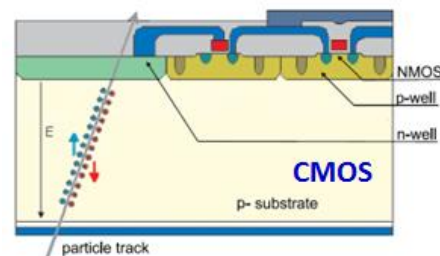
Participation to the design of a HVMAPS demonstrator (full-monolithic)

A full-monolithic version is already under study by some other research institutes (BONN, SLAC, KIT)

Few technologies under evaluation



- Option under discussion for ATLAS ITK external layers
- Very attractive for other experiments (@FCC) and other application (medical imaging)



Participation to R&D effort on FE-I5 chip design (through RD53 collaboration)

R&D program aims at developing Front End Elect ASIC for ATLAS and CMS through RD53 collaboration ⇒ FE-I5

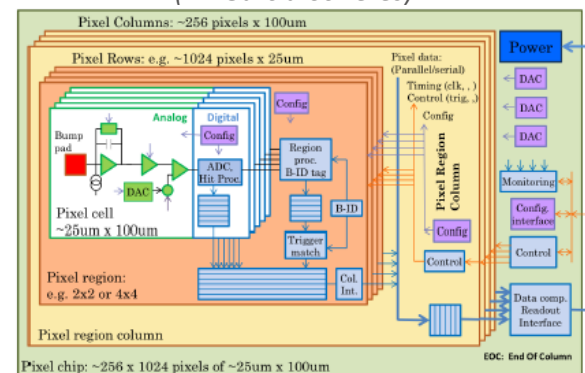
Technology chosen: TSMC 65 nm



Back-up solution to consider in case of absence of HVCMOS (or HVMAPS) in the inner tracker

“Analog islands in digital sea”

(M. Garcia-Sciveres)



Pixel chip hierarchical organization

SEDI perimeter + SIS expertise

Capacitive coupling by glue is an innovative/recent concept

 Interconnecting process studies

- Tools design, real. and tests with chips protos
- Assembly Process
- Material choice

 Develop and/or test some diagnostics to characterize glue quality layer

 Prototypes mech. characterization (ageing effect, fatigue effects,...)

 Reproducibility, yield

 Investigate options for future industrialization of the interconnection process

→ Participate right now to play a role for future participation in modules production

Example of glue deposition with pillars
(G. Darbo-INFN Genoa)

Spin SU-8 photoresist
Pattern pillars by mask

R/O CHIP

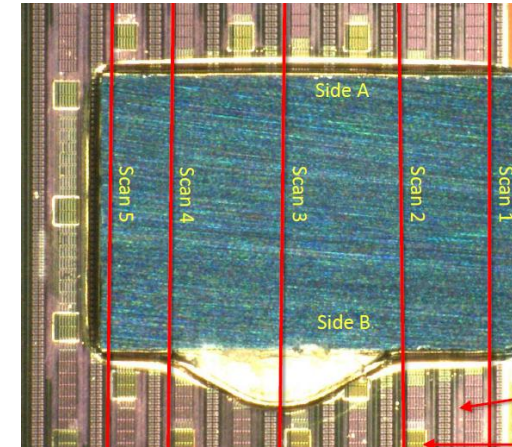
Glue deposition

R/O CHIP

Align & pressure

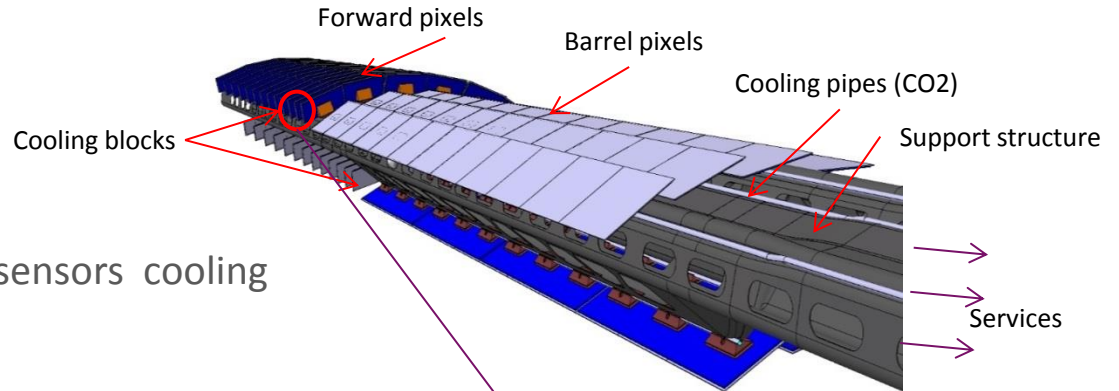
DETECTOR CHIP

R/O CHIP

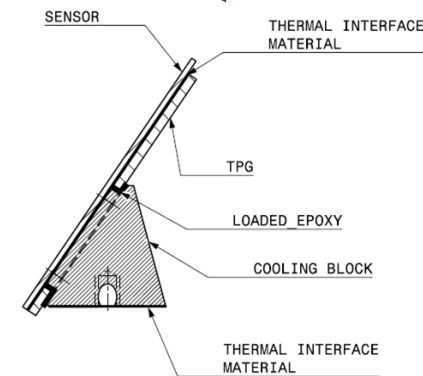


SIS perimeter

- ❑ Design studies of light material for sensors cooling blocks (thermal calculations)
- ❑ Thermal interfaces studies with prototypes realization
- ❑ New concept of cooling blocks deposit on support structure (test concept with 3D printer)
- ❑ Design study of outermost layers → interaction with physicists and follow ITK layout studies
- ❑ Routing and accurate assessment of services → regular interactions with collaboration



SLIM concept
(S. Michal's talk –UNI Geveve)



Tilted cell design

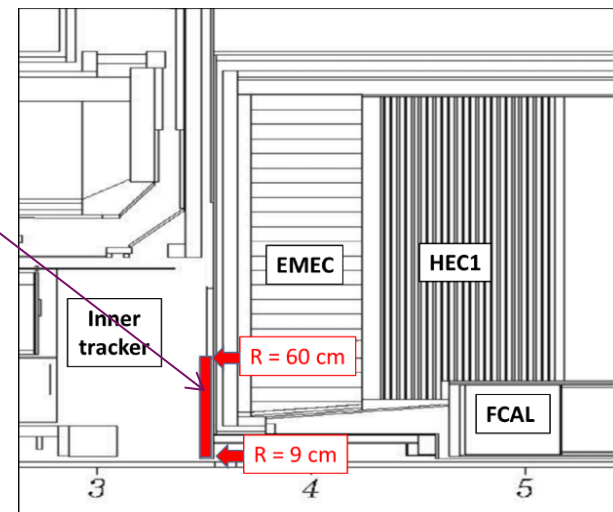
New detector to cope against pile-up effect in forward region

Main constraints:

- Time resolution of a few tens of ps
- Granularity better than 1 mm
- Important radiation levels comparable to first layers of ITK

2 options are considered at IRFU:

- Si pixels (HVCMOS) → new approach ≠ HVCMOS dev. for ITK
- Gaseous detector (Micromegas)



Technology options: intermediate milestones (F. Lanni)

- Oct 2015 - Sep 2016: R&D on sensors – prototypes
- Jul 2016 - Mar 2017: Test-beams and validation
- Mar 2017: Decision baseline technology [ATLAS]

- ❑ MAPS technology is nowadays sufficiently valid and mature for large physics experiments and has demonstrated excellent performances for charged particles tracking

- ❑ Strong experience in standard monolithic CMOS pixels sensors design/validation at IRFU
 - Regular Partner in European projects: FP6 (EUDET), FP7 (AIDA), H2020 (AIDA2020)
 - Active participation in large collaboration: (ILC), ALICE upgrade (close work with CERN micro-elect design team)

- ❑ New challenge for IRFU group for ATLAS Phase 2 ITK project → HVCMOS/HVMAPS
 - R&D effort started beginning of 2015 for pixels sensor design
 - Good relationship with collaborators (BONN, CPPM, ...)
 - Excellent perspectives in case of success for ATLAS ITK but not only (FCC, other)
 - Strong support of IRFU hierarchy to this activity is mandatory to succeed

Thank you for your attention

S. Rozanov – CPPM

- ❑ **Inner pixel layers** ($R=3-6$ cm) → Use of FE-RD53 in 65nm technology with 50×50 μm pixel size. Four CMOS 25×25 μm sub-pixels with thickness < 50 μm . Strong radiation hardness demand up to 1 GRads
- ❑ **Intermediate pixel layers** $R=6-25$ cm → Use of FE-RD53 with 50×50 μm pixel size. Four CMOS 25×25 μm sub-pixels with thickness < 50 μm interesting, but not mandatory.
- ❑ **Outer pixel layers** $R > 25$ cm → Use FE-lx digital tier with pixel 50×250 μm . Low cost bonding (gluing or C4 bumps) mandatory for cost reasons.
- ❑ **Outer pixel layers** $R > 25$ cm → Use Full monolithic CMOS chip with classical column readout